



09/612551

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLN. OF: TANABE et al.  
PATENT NO: 6,861,614  
ISSUED: March 1, 2005  
FOR: System for the Formation of a Silicon thin Film...  
DOCKET: NEC WNZ-2212

Commissioner for Patents  
Decisions and Certificates of Correction Branch  
P.O. Box 1450  
Alexandria, VA 22313-1450

**PETITION FOR CERTIFICATE OF CORRECTION**

Dear Sirs:

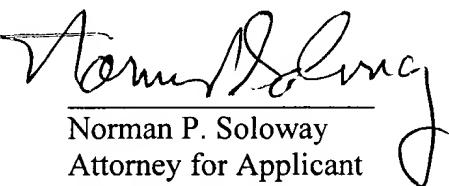
Reference is made to the attached letter mailed June 24, 2005.

The error does not concern the exclusion of the term "A". Rather term "A" was changed to "S" so that the title now reads "S System for the Formation of a Silicon Thin Film...". This makes not sense. Accordingly, we again respectfully request that a Certificate of Correction be issued that the title correctly reads "A System for the Formation of a Thin Film...", or simply reads "System for the Formation of a Silicon Thin Film".

No fee is believed necessary.

Respectfully submitted,

**Certificate**  
**AUG 31 2005**  
**of Correction**

  
\_\_\_\_\_  
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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Decisions and Certificates of Correction Branch, P.O. Box 1450, Alexandria, VA 22313-1450, on August 19, 2005 at Tucson, Arizona.

By:

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NEC UNZ-2212

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**COPY**

Date: *6-24-05*

Patent No.: 6,861,614 B1

Issued : March 1, 2005

Inventor : Tanabe, et al.

Title : **S SYSTEM FOR THE FORMATION OF A SILICON THIN FILM AND A SEMICONDUCTOR-INSULATING FILM INTERFACE**

Docket No :

Re: Request for Certificate of Correction

Consideration has been given your request for the issuance of a certificate of correction, for the above-identified patent under the provision of Rule 1.322 or R 1.323.

Respecting the alleged error, on the title page item [54], it is the practice to exclude words such as "Improvements in", "New", "A", "Novel", etc., from the printed patent. Therefore, no correction(s) is in order here under United States Codes (U.S.C.) 254 or 255 the Code of Federal Regulation (C.F.R.) R 1.322 R 1.323.

In view of the foregoing, your request is hereby denied.

Further correspondence concerning this matter should be filed and directed to Decisions and Certificates of Correction Branch. Any response must be filed within a four week period.

Valerie Jackson  
Newman Cecelia  
Decisions & Certificates  
of Correction Branch  
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